

Plano™ XY & XYZ Microscope Stage with Piezo Drive

Low-Profile, Low-Cost Nanopositioning Systems for Super-Resolution Microscopy



PI nano™ series nanopositioning stages feature a very low profile of 20 mm (0.8), a large aperture for 3 x 1" slides and deliver highly accurate motion with sub-nanometer resolution in up to 3 axes. Slide / petri dish holders optional

microscopy and imaging applications.

Cost Effective Design, High Performance

PI nano™ series piezo positioning stages are designed to provide high performance at minimum cost. For highly-stable, closed loop operation, piezoresistive sensors are applied directly to the moving structure and precisely measure the displacement of the stage platform. The very high sensitivity of these sensors provides optimum position stability and responsiveness as well as nanometer resolution. A proprietary servo controller significantly improves the motion linearity compared to conventional piezoresistive sensor controllers.

High Reliability and Long Lifetime

The compact P-545 systems are equipped with preloaded PICMA® high-performance piezo actuators which are integrated into a sophisticated, FEA-modeled, flexure guiding system. The PICMA® actuators feature cofired ceramic encapsulation and provide better performance and reliability than conventional piezo actuators. Actuators, guidance and sensors are maintenance-free, not subject to wear and offer extraordinary reliability.

- **Low Profile for Easy Integration: 20 mm (0.8")**
- **Up to 200 x 200 x 200 μm Travel Ranges**
- **Large Clear Aperture for 3 x 1" Slides**
- **Recessed Sample Holders for Maximized Utility Available**
- **Outstanding Lifetime Due to PICMA® Piezo Actuators**
- **Cost-Effective Design due to Piezoresistive Sensors**
- **Compatible w/ Leading Image Acquisition Software Package**
- **Closed-Loop Control for High Repeatability and Accuracy**
- **Millisecond Step Time, Ideal for Super-Resolution Microscopy**
- **24-Bit Controller w/ USB, Ethernet, RS-232 Interface and Analog Control**
- **Available Manual Long-Travel Stage with Motor Upgrade Option**

Long Travel, Low Profile, Optimized for Microscopy

PI nano™ XY and XYZ low-profile piezo scanning stages are optimized for easy integration into high-resolution micro-

scopes. They feature a very low profile of 20 mm (0.8") and a large aperture designed to hold Petri dishes and standard slide holders. The long travel ranges of up to 200 x 200 x 200 μm with nanometer closed-loop resolution are ideal for leading-edge

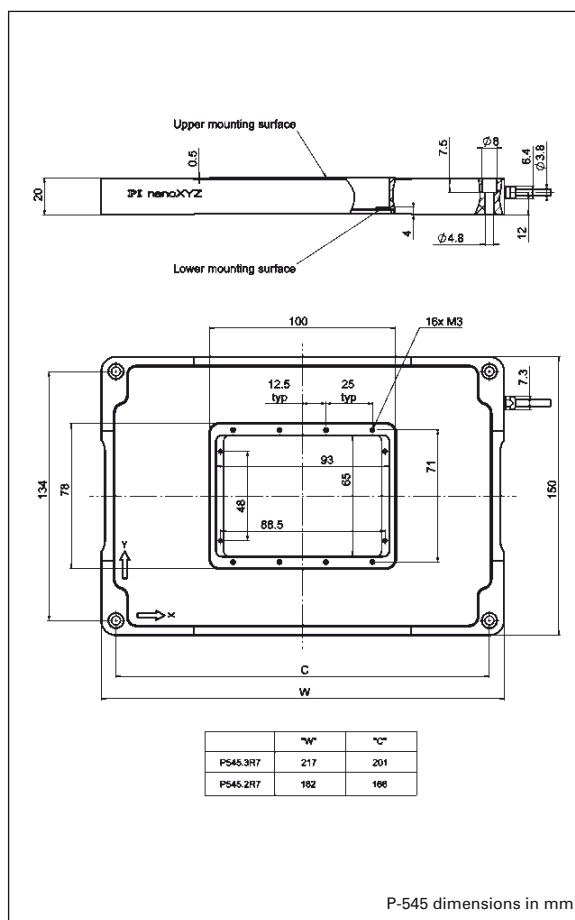
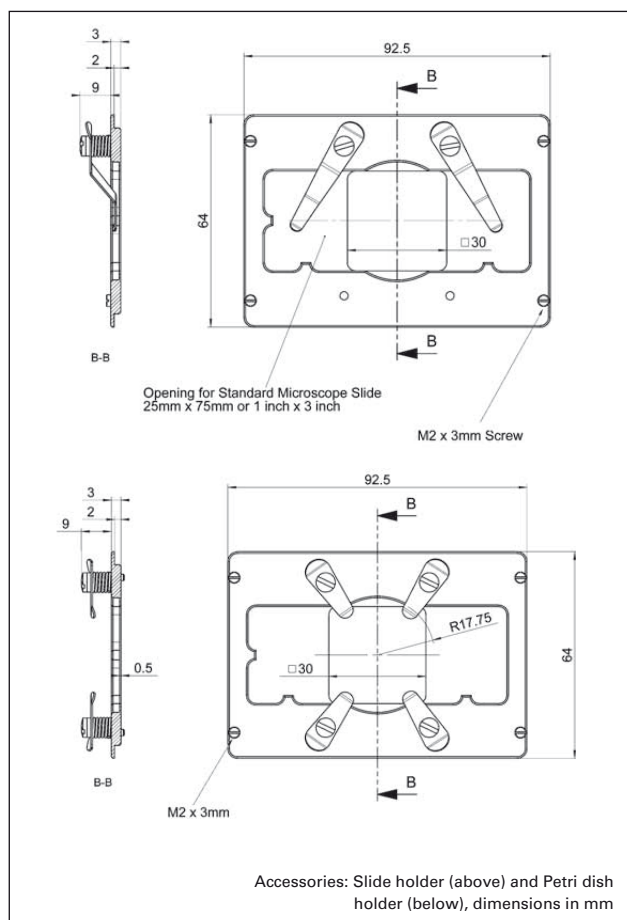
Application Examples

- Super-resolution microscopy
- 3D Imaging
- Laser technology
- Interferometry
- Metrology
- Biotechnology
- Screening
- Micromanipulation



Background: the piezo controller is included and comes with a 24-bit resolution USB port as well as ethernet, RS-232 and analog interface. Foreground: The optional M-545 manual XY stage provides a stable platform for the PI nano™ piezo stages. Custom stage version shown

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Technical Data

Model	P-545.2R7	P-545.3R7	Unit	Tolerance
Active axes	X, Y	X, Y, Z		
Motion and positioning				
Integrated sensor	piezoresistive	piezoresistive		
Closed-loop travel	200 x 200	200 x 200 x 200	μm	
Closed-loop resolution*	1	1	nm	typ.
Linearity	±0.1	±0.1	%	typ.
Repeatability	< 5	< 5	nm	typ.
Mechanical properties				
Push/pull force capacity	100 / 30	100 / 30	N	max.
Load	50	50	N	max.
Drive properties				
Ceramic type	PICMA® P-885	PICMA® P-885		
Electrical capacitance	6	6 (X, Y), 12 (Z)	μF	±20%
Miscellaneous				
Operating temperature range	-20 to 80	-20 to 80	°C	
Material	Aluminum	Aluminum		
Mass	1	1.2	kg	±5%
Cable length	1.5	1.5	m	±10 mm
Sensor / voltage connection	Sub-D, 25 pin	Sub-D, 25 pin		
Piezo controller (included in delivery)	E-545	E-545		

* Resolution of PI Piezo Nanopositioners is not limited by friction or stiction. Value given is noise equivalent motion measured with interferometer.